Amendments to the Claims

1. (Currently Amended) A vacuum deposition apparatus comprising:

a susceptor for heating a glass substrate, a portion of the susceptor providing an area used as a sliding portion on which to slide the glass substrate to a desired position;

lift pins for supporting the glass substrate ~~on the susceptor~~;

a robot arm for transferring the glass substrate onto the susceptor and returning the glass substrate from the susceptor; and

a groove formed in said portion of the susceptor for receiving material ~~scraped from a surface of the susceptor by a leading edge of the glass substrate~~ resulting from ~~during~~ sliding of the glass substrate on the surface of the susceptor.

2. (Currently Amended) The vacuum deposition apparatus according to claim 1, wherein a ~~length of gap between a beginning of~~ said sliding portion, measured from ~~of said substrate and~~ said groove, is at least 3 mm; ~~the beginning of said portion being the position on the susceptor where the leading edge of the glass substrate first touches the susceptor during sliding~~.

3. (Currently Amended) The vacuum deposition apparatus according to claim 2, wherein a length of said sliding portion, measured from said ~~groove, gap~~

is 10 mm.

4. (Previously Presented) The vacuum deposition apparatus according to claim 1, wherein the susceptor is made of a quartz material.

5. (Currently Amended) The vacuum deposition apparatus according to claim 1, wherein the section of said groove formed in ~~the sliding~~ said portion ~~of the susceptor~~ has a polygonal configuration.

6. (Currently Amended) The vacuum deposition apparatus according to claim 1, wherein the bottom face of the groove formed in ~~the sliding~~ said portion ~~of the susceptor~~ has a curved configuration.

7. (Currently Amended) The vacuum deposition apparatus according to claim 1, wherein the bottom face of the groove formed in ~~the sliding~~ said portion ~~of the susceptor~~ includes an incline plane and a perpendicular plane.

8. (Currently Amended) The vacuum deposition apparatus according to claim 1, wherein the groove formed in ~~the sliding~~ said portion ~~of the susceptor~~ has a V-shaped configuration.